Oxide Polishing Mechanism of Nanoceria

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Dr. Satyouki Nomura received the Ph.D. in the department of engineering from Osaka University (Japan) in 1998.

Thereafter he joined to Hitachi Chemical Co., Ltd. (currently Showa Denko Materials) R&D Center. He was developing anisotropic conducting film from 1998 to 2001, organic light emitting diode materials from 2001 to 2005. He studied organic thin film transistor materials at Cornell University (USA) as a visiting scientist from 2005 to 2007. After that, he developed Smart Glass (Smart Window) technology from 2007 to 2014. From 2015 he joined CMP R&D department and has been in charge of basic study of CMP process such as polishing mechanism.